

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: ) Confirmation No.: 9270  
Koichiro TANAKA et al. ) Examiner: Hung D. Nguyen  
Serial No. 10/582,013 ) Group Art Unit: 3742  
Filed: June 7, 2006 )  
For: LASER IRRADIATION METHOD, )  
IRRADIATION APPARATUS, AND )  
METHOD FOR FABRICATING )  
SEMICONDUCTOR DEVICE )

**AMENDMENT AND RESPONSE TO ELECTION REQUIREMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Specification** begin on page 1 of this paper.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 11 of this paper.